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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):

Thomas McWaid et al.

Title:

System For Sensing A Sample

Application No.:

10/729,609

Filing Date:

December 5, 2003

Examiner:

Not yet assigned

Group Art Unit:

2856

Docket No.:

TNCR.169US2

Conf. No.:

2888

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, Applicants call the documents listed on the enclosed Form PTO-1449 to the Examiner's attention in this patent application. Copies of the documents listed on the accompanying Form PTO-1449 were previously submitted in Application No. 09/313,962, filed May 18, 1999, now U.S. Patent No. 6,520,505, Application No. 08/730,641, now U.S. Patent No. 5,948,972, issued September 7, 1999, and Application No. 08/362,818, filed December 22, 1994, now U.S. Patent No. 5,705,741, issued January 6, 1998, from which this Application claims an earlier effective filing date.

Citation of these documents shall not be construed as (1) an admission that the documents are prior art with respect to the invention or inventions claimed in this application, (2) a representation that a search has been made (other than as indicated by any cited document), or (3) an admission that the cited information is, or is considered to be, material to patentability as defined in § 1.56(b).

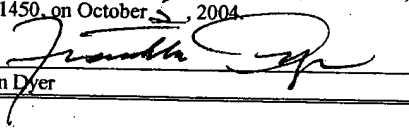
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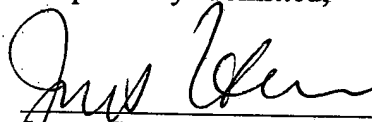


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Franklin Dyer

Respectfully submitted,



James S. Hsue
Reg. No. 29,545

10/5/04
Date

U.S. Department of Commerce, Patent and Trademark

Atty. Docket No.

Application No.

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	3	3,283,568	Nov., 1966	Reason.			
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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